	Application No.	Applicant(s)	
Notice of Allowability	10/791,026	CHEN ET AL.	
	Examiner	Art Unit	
	Michael P. Stafira	2877	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to *after final amaendment filed 8/17/2005*.

2. ☒ The allowed claim(s) is/are *50,53-72,75,76,79-98,100,102,105-124 and 127*.

3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).

    a) ☐ All   b) ☐ Some*   c) ☐ None   of the:

        1. ☐ Certified copies of the priority documents have been received.

        2. ☐ Certified copies of the priority documents have been received in Application No. _____ .

        3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

    * Certified copies not received: _____ .

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.

5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.

    (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached

        1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____ .

    (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____ .

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).

6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. ☐ Notice of References Cited (PTO-892)

2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)

3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08), Paper No./Mail Date _____

4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material

5. ☐ Notice of Informal Patent Application (PTO-152)

6. ☐ Interview Summary (PTO-413), Paper No./Mail Date _____ .

7. ☐ Examiner's Amendment/Comment

8. ☒ Examiner's Statement of Reasons for Allowance

9. ☐ Other _____ .

DETAILED ACTION

Allowable Subject Matter

1.   Claims 50, 53-72, 75-76, 79-98, 100, 102, 105-124, 127 are allowed over the prior art of

record.

2.   The following is an examiner's statement of reasons for allowance:

Regarding claim 50, the prior art fails to disclose or make obvious a method for detecting

and classifying anomalies of a surface of a sample of a material suitable for use as a substrate for

storage, display or electronic device having the steps of analyzing uses more than one threshold

to analyze the detector output and to arrive at least one classification of the anomalies, said

analyzing and classifying comprising processing the output with a first threshold, and classifying

the anomalies in a first classification and analyzing the output with a second threshold different

from the first threshold. said classifying including applying algorithms to test relationship

between anomalies, if any, wherein the output is analyzed with a second threshold without

applying the algorithm to test relationship between anomalies, and in combination with the other

recited limitations of claim 50. Claims 53-71 are allowed by the virtue of dependency on the

allowed claim 50.

Regarding claim 72, the prior art fails to disclose or make obvious a method for detecting

and classifying anomalies of a surface of a sample having the steps of processing the detector

output with a first thresholds and classifying the anomalies in a first classification; wherein the

analyzing and classifying analyzes the detector output and uses the classification information to

arrive at least one classification of the anomalies, said analyzing and classifying also analyzing

the output with a second threshold different from the first threshold, said providing including

applying algorithm to test relationship between the anomalies if any wherein said analyzing and classifying analyze the detector output with a second threshold without applying the algorithm to test relationship between anomalies, and in combination with the other recited limitations of claim 72. Claim 75 is allowed by the virtue of dependency on the allowed claim 72.

Regarding claim 76, the prior art fails to disclose or make obvious a method for detecting and classifying anomalies of surface of a sample of a material suitable for use as a substrate for storage, display or electronic devices having the steps of analyzing uses more than one threshold to analyze the detector output and to arrive at least one classification of the anomalies said analyzing and classifying comprising processing the-output with a first threshold, and classifying the anomalies in a first classification and analyzing the output with a second threshold different from the first threshold and wherein the processing of the output with the first threshold and the analyzing of the output with a second threshold are performed independently of one another, and in combination with the other recited limitations of claim 76. Claims 79-85, 94, 97 are allowed by the virtue of dependency on the allowed claim 76.

Regarding claim 86, the prior art fails to disclose or make obvious a method for detecting and classifying anomalies of surface of a sample of a material suitable for use as a substrate for storage, display or electronic devices having the steps of wherein the analyzing uses more than one threshold to analyze the detector output and to arrive at least one classification of the anomalies, wherein the classifying the anomalies by means of their distribution over the surface, and in combination with the other recited limitations of claim 86. Claims 87-93, 95-96, are allowed by the virtue of dependency on the allowed claim 86.

Regarding claim 98, the prior art fails to disclose or make obvious a method for detecting and classifying anomalies of surface of a sample of a material suitable for use as a substrate for storage, display or electronic devices having the steps of wherein the analyzing and classifying analyzes the detector output and uses the classification information to arrive at least one classification of the anomalies, said providing comprising processing the detector output with a first threshold and classifying the anomalies in a first classification and said analyzing and classifying analyzing the output with a second threshold different from the first threshold, said analyzing and classifying comprising using the first classification and the output analyzed with a second threshold to characterize anomalies in the detector output analyzed with a second threshold, and in combination with the other recited limitations of claim 98. Claim 100 is allowed by the virtue of dependency on the allowed claim 98.

Regarding claim 102, the prior art fails to disclose or make obvious a method for detecting and classifying anomalies of surface of a sample of a material suitable for use as a substrate for storage, display or electronic devices having the steps of wherein the analyzing uses more than one threshold to analyze the detector output and to arrive at least one classification of the anomalies, said analyzing and classifying comprising processing the output with a first threshold, and classifying the anomalies in a first classification and analyzing the output with a second threshold different from the first threshold and wherein the processing of the output with the first threshold and the analyzing of the output with a second threshold are performed independently of one another, and in combination with the other recited limitations of claim 102. Claims 105-123 are allowed by the virtue of dependency on the allowed claim 102.

Regarding claim 124, the prior art fails to disclose or make obvious a method for detecting and classifying anomalies of surface of a sample of a material suitable for use as a substrate for storage, display or electronic devices having the steps of wherein the analyzing and classifying analyzes the detector output and uses the classification information to arrive at least one classification of the anomalies, said providing comprising processing the detector output with a first threshold, and classifying the anomalies in a first classification, and said analyzing and classifying analyzing the output with a second threshold different from the first threshold. applying algorithm to test relationship between the anomalies, if any, wherein said analyzing and classifying analyze the detector output with a second threshold without applying the algorithm to test relationship between anomalies, and in combination with the other recited limitations of claim 124. Claim 127 is allowed by the virtue of dependency on the allowed claim 124.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michael P. Stafira whose telephone number is 571-272-2430. The examiner can normally be reached on 4/10 Schedule Mon.-Thurs..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Gregory Toatley can be reached on 571-272-2800 ext. 77. The fax phone number for

the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent

Application Information Retrieval (PAIR) system. Status information for published applications

may be obtained from either Private PAIR or Public PAIR. Status information for unpublished

applications is available through Private PAIR only. For more information about the PAIR

system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR

system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Michael P. Stafira
Primary Examiner
Art Unit 2877

August 31, 2005